

T14

Notice of Allowability

Application No.

09/633,782

Examiner

HOAN C. NGUYEN

Applicant(s)

LEE ET AL.

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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to 2/6/07.
2. ☒ The allowed claim(s) is/are 1,2,7,8,12,15,19-22,24 and 25.
3. ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
 - a) ☒ All b) ☐ Some* c) ☐ None of the:
 1. ☒ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

* Certified copies not received: _____.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
 5. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
 - (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
 - 1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____.
 - (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____.
- Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

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| <ol style="list-style-type: none"> 1. <input type="checkbox"/> Notice of References Cited (PTO-892) 2. <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) 3. <input type="checkbox"/> Information Disclosure Statements (PTO/SB/08),
Paper No./Mail Date _____ 4. <input type="checkbox"/> Examiner's Comment Regarding Requirement for Deposit
of Biological Material | <ol style="list-style-type: none"> 5. <input type="checkbox"/> Notice of Informal Patent Application 6. <input type="checkbox"/> Interview Summary (PTO-413),
Paper No./Mail Date _____ 7. <input checked="" type="checkbox"/> Examiner's Amendment/Comment 8. <input checked="" type="checkbox"/> Examiner's Statement of Reasons for Allowance 9. <input type="checkbox"/> Other _____ |
|---|---|

EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it **MUST** be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Mr. David Bilodeau (the register number of 42325) on April 12, 2007.

Mr. Bilodeau authorizes the following changes:

Lines 30-32 in claim 1 change into:

"wherein the thin film transistor further includes a gate light absorbing film formed only under the gate line and the gate electrode, a source light absorbing film formed only under the source electrode and the data line, and a drain light absorbing film formed only under the drain electrode."

Lines 16-17 in claim 12 change into:

forming a gate light absorbing film only under the gate electrode and the gate line;

forming a source light absorbing film formed only under the source electrode and the data line;

DETAILED ACTION

Claims 3-6, 9-11, 13-13, 16-18 and 23 have been cancelled.

Applicants admitted the amended feature supported by Fig. 5, which shows the a gate light absorbing film, a source light absorbing film and a drain light absorbing film are three separated films.

Besides, in specification, the light absorbing films specifically are made of oxidation film, nitride film or black resin. The examiner does not consider a reflecting film made of aluminum, for instance, to be a "light absorbing film".

Allowable Subject Matter

Claims 1-2, 7-8, 12, 15, 19-22 and 24-25 are allowed.

Reasons for Allowance

Claims 1 and 12 are allowed sine there is no prior art teaches a liquid crystal display device with a upper substrate comprising a thin film transistor on the upper substrate, passivation film on the upper substrate and covering the transistor, and color filter over the pixel electrode which is formed on the passivation film, wherein the thin film transistor includes a gate light absorbing film formed only under the gate electrode, a source light absorbing film formed only under the source electrode, and a drain light absorbing film formed only under the drain electrode.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

The prior art made of record and not relied upon is considered pertinent to applicant's disclosure:

Otoguro et al. (JP401052129A) disclose the a source light shielding film 11 forming under a source electrode and a gate electrode and a drain light shielding film 11 forming under a drain electrode and a gate electrode.

Sato et al. (US 5708485 A) disclose the active matrix display device including a mask shielding film 16M covering a source electrode and gate electrode and a mask shielding film 16P covering a drain electrode under the pixel electrode.

Murade et al. (US 20020024622 A1) disclose placement of a first light shielding film (7) at least below the channel region (1c) of a TFT which drives a pixel, and of a second light shielding film (3) above the same prevents impingement of light coming from above or from below on that channel region (1c) Further, a second light shielding film (3) is formed to cover the channel region (1c) and the first light shielding film (7)

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thereby to prevent the surface of the first light shielding film (7) from direct exposure to light


Any inquiry concerning this communication or earlier communications from the examiner should be directed to HOAN C. NGUYEN whose telephone number is (571) 272-2296. The examiner can normally be reached on MONDAY-THURSDAY:8:00AM-4:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on (571) 272-1787. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

HOAN C. NGUYEN
Examiner
Art Unit 2871

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ANDREW C. HECHTER
PRIMARY EXAMINER